

ePAD™* WAFER PROTECTION SYSTEM

High performance alternative to foam-based solutions

- Made from proprietary, low-ionic, flexible, conductive polystyrene
- Ideal for both Cu and Al metallized wafers
- Best choice for both long and short term storage needs
- Available for 6", 8" and 12" wafer sizes

WAFER CANISTER LID PLATFORM **ePAD CUSHION PLATFORM ePAD CUSHION SEPARATOR** WAFER SEPARATOR WAFER SEPARATOR **PLATFORM ePAD CUSHION PLATFORM** ePAD CUSHION WAFER CANISTER BASE

(PATENTS: US #7425362, Singapore #105587, Japan #4205540, Taiwan #1297662, PRC#ZL 03 2 07819.6)



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